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Sheet 1 of 1
**FIRST IDS LIST OF REFERENCES
CITED BY APPLICANT
(FORM PTO-1449)**
DATED: March 14, 2005

Atty. Docket No. 017527789 PCT/PTO 4856/PCT	Serial No.: To Be Assigned
Applicant: Matthias AIKELE et al.	
U.S. Filing Date: March 14, 2005	Art Unit:

U. S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NO.	DATE	NAME	Cl.	Sub-Cl.	Fil. Date
	AA	5,041,898	08/1991	Urabe et al.	-	-	-
	AB	5,747,377	05/1998	Wu	-	-	-
	AC	5,930,595	07/1999	Sridhar et al.	-	-	-
	AD	6,239,473	05/2001	Adams et al.	-	-	-
	AE	6,342,427	01/2002	Choi et al.	-	-	-

FOREIGN PATENT DOCUMENTS

		DOCUMENT NO.	DATE	COUNTRY	Cl.	Sub-Cl.	Trans.	
							Yes	No

OTHER DOCUMENTS

<input checked="" type="checkbox"/>	AF	Chunbo Zhang et al.; "Fabrication of thick silicon dioxide layers using DRIE, oxidation and trench refill"; IEEE, 2002, pages 160-163, XP010577620 no month available

EXAMINER'S SIGNATURE

/Anita Alanko/ (08/02/2010)

DATE CONSIDERED

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ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /A.A./ (08/02/2010)

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